



제 31회 한국반도체학술대회

The 31st Korean Conference on Semiconductors

2024년 1월 24일(수)-26일(금) | 경주화백컨벤션센터(HICO)

2024년 1월 26일(금), 13:45-15:30

Room L(206), 2층

Q. Metrology, Inspection, Analysis, and Yield Enhancement 분과

[FL2-Q] Metrology, Inspection, and Yield Enhancement III

좌장: 강상우 소장(한국표준과학연구원), 정용우 TL(SK 하이닉스)

<p>FL2-Q-1 13:45-14:00</p>	<p>Wafer Inspection with High-speed Microdeflectometry Manh Nguyen The¹, Young-Sik Ghim^{1,2}, and Hyug-Gyo Rhee^{1,2} ¹KRISS, ²UST</p>
<p>FL2-Q-2 14:00-14:15</p>	<p>FTIR 및 기계학습을 활용한 SiN에 미치는 방사선 영향 분석 Dong-Hyeon Kim and Sung-Uk Zhang Digital Twin Laboratory, Dong-Eui University</p>
<p>FL2-Q-3 14:15-14:30</p>	<p>Strain-enhanced Ion Drift Localization of 2D Van der Waals Ferroelectric Heterojunction via Tip-induced Strain Engineering Jinhyoung Lee¹, Gunhoo Woo^{2,3}, Jinill Cho¹, Yoonseok Noh⁵, Hyelim Shin⁵, Donghyuk Choi⁶, and Taesung Kim^{1,2,3,4,5} ¹School of Mechanical Engineering, Sungkyunkwan University, ²SKKU Advanced Institute of Nanotechnology, Sungkyunkwan University, ³Department of Nano Science and Technology, Sungkyunkwan University, ⁴Department of Nano Engineering, Sungkyunkwan University,</p>
<p>FL2-Q-4 14:30-14:45</p>	<p>Development of Physical Force-Assisted Wet Cleaning Process for Removing Highly Chemically Resistant Organic Residue Jae-Hyeong Lee¹, Tae-Yoon Jung¹, Kyoung-Chae Seo², Byoung-Pil Lee², Eun-Jin Kim², Han-Ku Cho², Jin-Goo Park¹, and Tae-Gon Kim¹ ¹Department of Materials Science and Chemical Engineering, Hanyang University ERICA, ²FST, Fine Semitech Corp.</p>
<p>FL2-Q-5 14:45-15:00</p>	<p>경화 공정 수율 증대를 위한 다물리기반 경화 해석 및 답러닝 네트워크 김경빈¹, 이은호^{1,2} ¹성균관대학교 기계공학과, ²성균관대학교 지능형 펩테크 융합전공</p>



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FL2-Q-6 15:00-15:15	Thermo-reflectance Microscope and Semiconductor Applications Ki Soo Chang ¹ , Dong Uk Kim ¹ , Chan Bae Jeong ¹ , Ilkyu Han ¹ , Dong Mok Kim ¹ , Seung-Woo Lee ² , and Byung-Seon Chun ² ¹ Division of Scientific Instrumentation, KBSI, ² Nanoscope Systems, Inc.
FL2-Q-7 15:15-15:30	Anomaly Classification for Multivariate Time-Series with Noisy Labels: A Semi-Supervised Approach Jun Hui Lee and PooGyeon Park Department of Electrical Engineering, POSTECH